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INFORMATION DISCLOSURE STATEMENT

(Use several sheets if necessary)

APPLICANTS
Yoshihito NARITA et al.FILING DATE
February 19, 2002

U.S. PATENT DOCUMENTS

| EXAMINER INITIAL | DOCUMENT NUMBER | DATE | NAME | CLASS | SUB CLASS |
|---------------------|-----------------|------|------|-------|--------------|
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FOREIGN PATENT DOCUMENTS

| | | DOCUMENT NUMBER | DATE | COUNTRY | CLASS | SUB CLASS |
|-------------|---|-------------------------------|------------|---------|-------|--------------|
| Aullah ↓ | 1 | JP A 2000-215499 (w/abstract) | 08/04/2000 | Japan | | |
| | 2 | JP A 2000-132856 (w/abstract) | 05/12/2000 | Japan | | |
| | 3 | JP A 2000-223767 (w/abstract) | 08/11/2000 | Japan | | |
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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

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| Aullah ↓ | 4 | Yatsui et al., "Subwavelength-sized phase-change recording with a silicon planar apertured probe", SPIE, Vol. 3791, pages 76-84, July 1999 |
| | 5 | Lee et al., "Nanometric aperture arrays fabricated by wet and dry etching of silicon for near-field optical storage application", J. Vac. Sci. Technol. B, Vol. 17, Number 6, pages 2462-2466, Nov/Dec 1999 |
| | 6 | Yatsui et al., "High-density-speed optical near-field recording-reading with a pyramidal silicon probe on a contact slider", OPTICS LETTERS, Vol. 25, No. 17, pages 1279-1281, September 2000 |
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EXAMINER

Akim Enayet Ullah

DATE CONSIDERED

Feb. 09 - 2004

Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Date: July 18, 2002